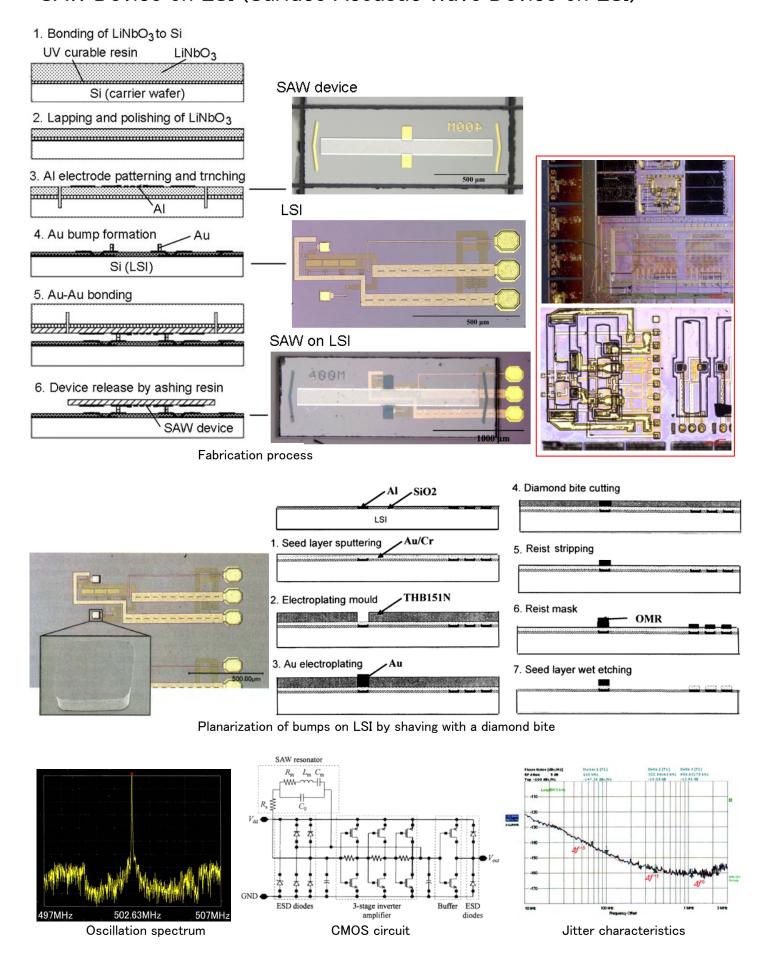
SAW Device on LSI (Surface Acoustic Wave Device on LSI)



Reference: K.D.Park, M.Esashi and S.Tanaka, Preparation of Thin Lithium Niobate Layer on Silicon Wafer for Wafer-level Integration of Acoustic Devices and LSI, Trans. of IEE in Japan, 130-E (2010) pp.236-241